

CONTENTS

List of abbreviations.....	10
Preface.....	11
Introduction	15
Chapter 1. Basic mathematical and physical models of micro- and nanoelectromechanical systems	17
1.1. Methods of engineering mathematics	17
1.2. Elements of multiphysical modeling	26
1.3. Statistical simulation methods.....	58
1.4. Physical effects analysis by scaling method.....	76
1.5. Mathematical modeling of measuring systems. Analysis of noise sources	86
1.6. Surfaces with random fluctuations of microstructure as a source of noise.....	104
1.7. Modeling of micromechanics of cantilever and membrane systems	111
Chapter 2. Materials and technology for MEMS	129
2.1. Basic active and constructive materials	129
2.2. Nanomaterials and nanostructures.....	131
2.3. Basic technologies of electronic materials.....	139
Chapter 3. Components of embedded microsystems	213
3.1. Physical principles of integration of MEMS as embedded microsystems.....	213
3.2. Basic models of sensors of physical quantities.....	229
3.3. Basic physical models of functioning of microinertial systems	247
3.4. Alloys of electromechanical systems.....	257
Chapter 4. CAD of micro- and nano-electromechanical systems and embedded systems	287
4.1. Physical and mathematical basic of CAD micro-and nanosystems	288
4.2. Embedded macro, micro and nanosystems and the principles of design.....	302
4.3. Design of sensor of inertia based on an Arduino and platform accelerometer	313
4.4. Design smart embedded systems	326
4.5. Instrumental design tools for “Smart home”	334
4.6. Modern trends in the design of high-tech smart nanosystems	335
Chapter 5. Workshop on computer simulation of basic phenomena and processes in micro and nanosystems	345